

09/700033

5373/PCT/dlm

529 Rec'd PCT/PTC-09 NOV 2000
BOX PCT

IN THE UNITED STATES DESIGNATED/ELECTED OFFICE (DO/EO/US)

In re Application of

BERND LOCHEL ET AL

U.S. Serial No.

Filed: November 9, 2000

METHOD OF AND APPARATUS FOR
DRYING PHOTO RESIST LAYERS

International Application No. PCT/DE99/01485
International Filing Date: May 12, 1999

Alexandria, Virginia
November 9, 2000

United States Designated/Elected Office (DO/EO/US)
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §1.97

Dear Sirs:

Applicant is submitting herewith a copy of the
following patent document:

European Patent Application 0 509 962 A1

The above listed documents are set forth
together with the applicants and issue or publication
date thereof in the attached PTO Form 1449.

Respectfully submitted,
BERND LOCHEL

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Attachments - PTO Form 1449 w/1 Document

